

**Amendments to the Specification:**

**Please delete the following section title and paragraph, which are found on page 1, lines 4-10:**

**TECHNICAL FIELD OF THE INVENTION**

The invention relates to making temporary, pressure connections between electronic components and, more particularly, to techniques for performing test and burn-in procedures on semiconductor devices prior to their packaging, preferably prior to the individual semiconductor devices being singulated from a semiconductor wafer.

**Please replace the paragraph on page 2, lines 2-13 in the specification as originally filed, with the following replacement paragraph:**

This patent application is a continuation of US Patent Application No. 994,799 filed December 19, 1997, which is a continuation of US Patent Application No. 08/789,147 filed January 24, 1997 (now US Patent No. 5,806,181), which is a continuation-in-part of commonly-owned, copending U.S. Patent Application No. 08/452,255 (hereinafter "PARENTCASE") filed 26 May 95, and its counterpart PCT patent application number PCT/US95/14909 filed 13 NOV 95, both of which are continuations-in-part which is a continuation-in-part of commonly-owned, copending U.S. Patent Application No. 08/340,144 filed 15 Nov 94 (now US Patent No. 5,917,707), and its counterpart PCT patent application number PCT/US94/13373 filed 16 Nov 94 (published 26 May 95 as WO 95/14314), both of which are continuations-in-part which is a continuation-in-part of commonly-owned, copending U.S. Patent Application No. 08/152,812 filed 16 Nov 93 (now USP 5,476,211, 19 Dec 95), all of which are incorporated by reference herein.

**Please insert the following new section title and paragraph immediately following line 31 on page 2:**

TECHNICAL FIELD OF THE INVENTION

The invention relates to making temporary, pressure connections between electronic components and, more particularly, to techniques for performing test and burn-in procedures on semiconductor devices prior to their packaging, preferably prior to the individual semiconductor devices being singulated from a semiconductor wafer.